

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Original) Method for production of a device for thermal detection of radiation comprising at least one active microbolometer (19) and at least one passive microbolometer (12), each comprising a suspended membrane (22) performing the function of radiation absorber, thermometer and electrical connection, the active (19) and passive (12) microbolometers being formed simultaneously on a single support substrate (16) and a reflective screen (17) being formed on the whole of the device, and then eliminated opposite the locations of the active microbolometers (19), method characterized in that, the membrane (22) comprising a thermometric element (14) and a radiation-absorbing element (13) performing the electrical connections, the passive microbolometer (12) is formed on the reflective screen (17) which comprises at least one metallic layer (18) in contact with the absorbing element (13) of the membrane (22).

2. (Original) Passive microbolometer (12) achieved by the method according to claim 1, characterized in that the reflecting screen (17) is arranged underneath the membrane (22), in contact with the absorbing element (13) of the membrane.

3. (Currently Amended) Microbolometer according to ~~one of claims 1 and 2~~ claim 1, characterized in that the thickness of the metallic layer (18) is about 500Å to 2000Å.